

ABSTRACT

A semiconductor device production apparatus includes a rotary table section including a rotary table for supporting a wafer thereon, a chamber for housing the rotary table section, a heater
5 provided in the chamber for heating the wafer, a temperature sensing device for sensing a temperature of the wafer, a temperature measuring section for converting the sensed temperature into a first signal to output the first signal, and a
10 signal generating section for converting the output first signal into a second signal detectable from outside the chamber.

The temperature sensing device, the temperature measuring section and the signal generating section are attached to the rotary table section.